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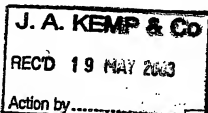
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Anmelder/Applicant/Demandeur/Patentinhäber/Proprietor/Titulaire ASML Netherlands B.V.	

## COMMUNICATION

The European Patent Office herewith transmits as an enclosure the European search report for the above-mentioned European patent application.

If applicable, copies of the documents cited in the European search report are attached.

☒ Additional set(s) of copies of the documents cited in the European search report is (are) enclosed as well.

The following specifications given by the applicant have been approved by the Search Division:

☐ abstract

☒ title

☒ The abstract was modified by the Search Division and the definitive text is attached to this communication.

The following figure will be published together with the abstract:

2.

## REFUND OF THE SEARCH FEE

If applicable under Article 10 Rules relating to fees, a separate communication from the Receiving Section on the refund of the search fee will be sent later.





DOCUMENTS CONSIDERED TO BE RELEVANT			
Category	Citation of document with indication, where appropriate, of relevant passages	Relevant to claim	CLASSIFICATION OF THE APPLICATION (Int.Cl.7)
X	EP 1 136 887 A (ASM LITHOGRAPHY BV) 26 September 2001 (2001-09-26) * paragraph '0023! - paragraph '0033! * * figures 1-4 *	1, 3-6, 8, 9	G03F7/20
X	PATENT ABSTRACTS OF JAPAN vol. 015, no. 291 (E-1093), 24 July 1991 (1991-07-24) & JP 03 102849 A (FUJITSU LTD), 30 April 1991 (1991-04-30) * abstract * * figures *	1, 3, 4, 9	
X	PATENT ABSTRACTS OF JAPAN vol. 018, no. 403 (E-1584), 27 July 1994 (1994-07-27) & JP 06 120131 A (SUMITOMO ELECTRIC IND LTD), 28 April 1994 (1994-04-28) * abstract * * figures *	1, 3	
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A	US 5 441 911 A (MALHI SATWINDER) 15 August 1995 (1995-08-15) * column 1, line 50 - column 2, line 4 * * figure 1 *	1-3	
The present search report has been drawn up for all claims			
Place of search THE HAGUE		Date of completion of the search 28 April 2003	Examiner Aguilar, M.
CATEGORY OF CITED DOCUMENTS			
X: particularly relevant if taken alone Y: particularly relevant if combined with another document of the same category A: technological background O: non-written disclosure P: intermediate document		T: theory or principle underlying the invention E: earlier patent document, but published on, or after the filing date D: document cited in the application L: document cited for other reasons &: member of the same patent family, corresponding document	

**ANNEX TO THE EUROPEAN SEARCH REPORT  
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EP 02 25 4878

This annex lists the patent family members relating to the patent documents cited in the above-mentioned European search report. The members are as contained in the European Patent Office EDP file on  
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ABSTRACT / ZUSAMMENFASSUNG / ABREGE

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A substrate holder (10) to adapt a small wafer (w) to a wafer table of a lithographic apparatus adapted to receive a larger wafer comprises a larger silicon wafer (11) with a burr pattern on which the small wafer is to be placed, positioning pins (12, 13) to locate the small wafer and a clamp formed by a clamp ring (15) and magnets (14) attached to the larger wafer.